Supporting Information

A fiber-shaped light-emitting pressure sensor for visualized dynamic monitoring

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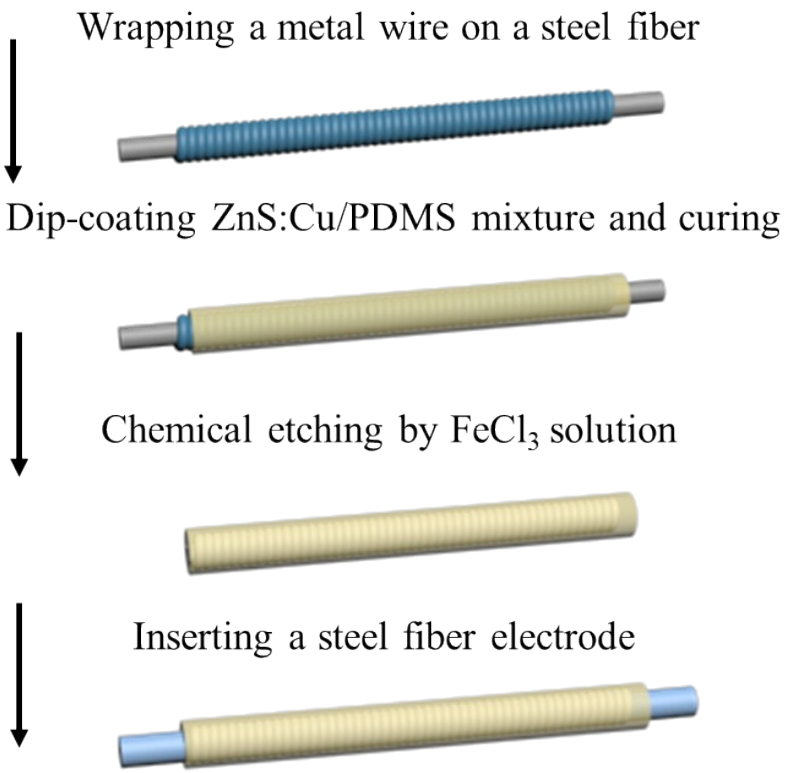

Fig. S1. Schematic illustration of preparing a fiber-shaped light-emitting pressure sensor.

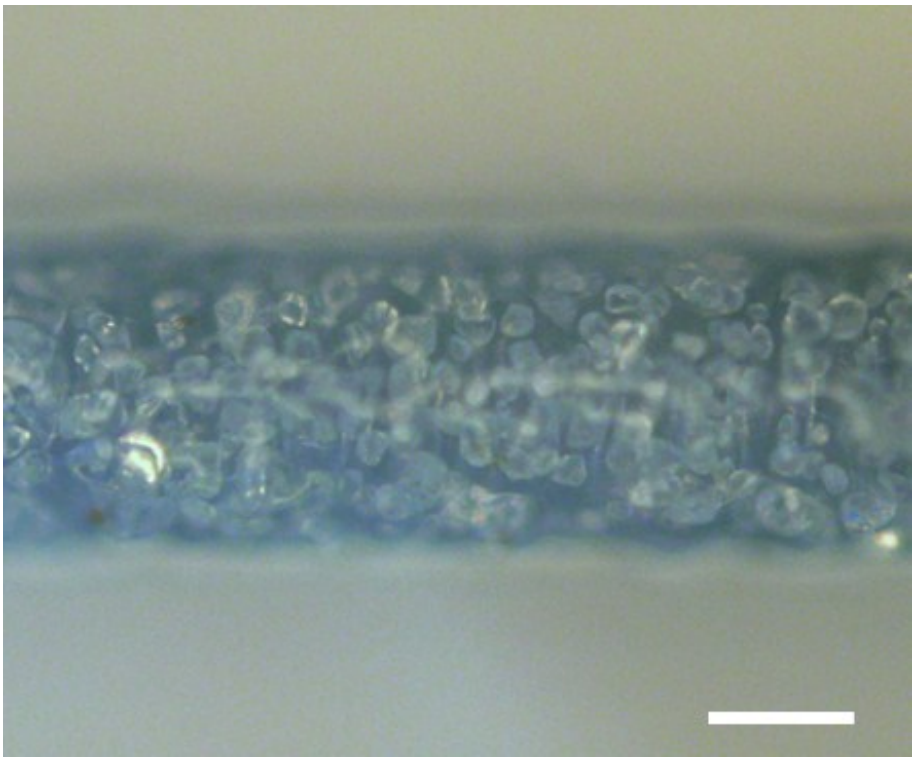

Fig. S2. Optical micrograph of a ZnS:Cu/PDMS hollow fiber. Scale bar, 100 μm.

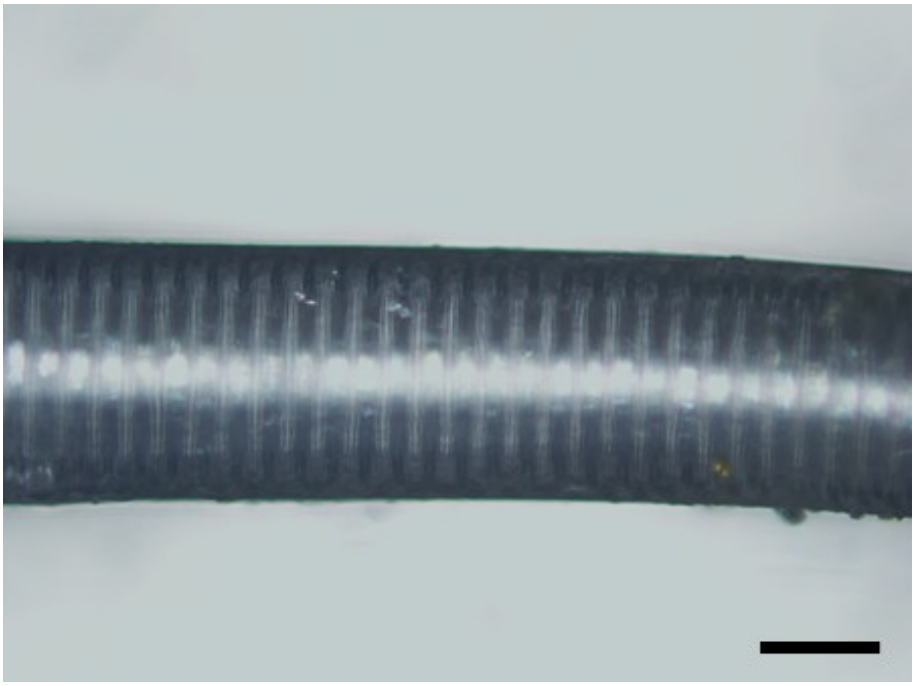

Fig. S3. Optical micrograph of a bare PDMS hollow fiber with uniaxial folded microstructures prepared by wrapping the copper fiber with a diameter of 30 μm. Scale bar, 100 μm.

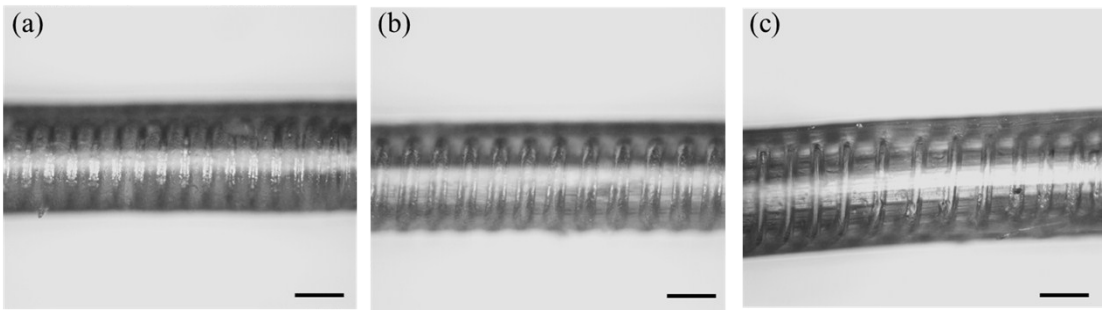

Fig. S4. Optical micrographs of bare PDMS hollow fibers with uniaxial folded microstructures with different distances of (a) 45 μm, (b) 60 μm, (c) 75 μm. Scale bar, 100 μm.

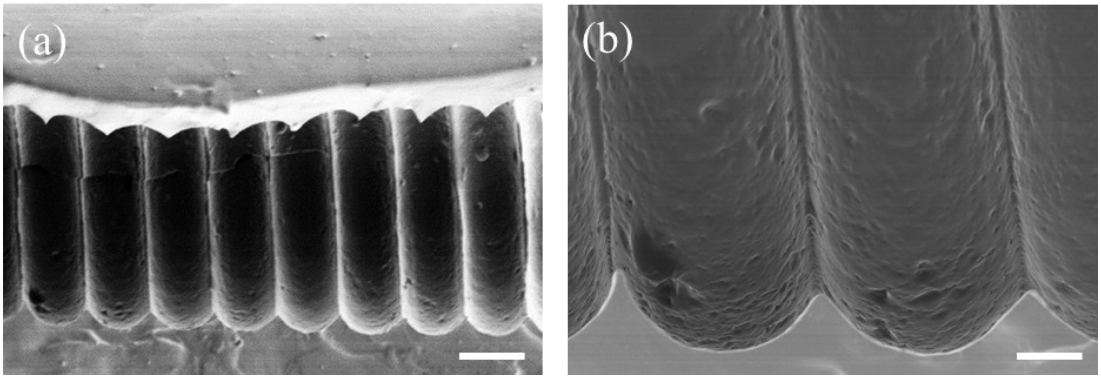

Fig. S5. SEM image of the bare PDMS hollow fiber with uniaxial folded microstructures in low magnification (a) and high magnification (b). Scale bars in a and b, 50 μm and 10 μm, respectively.

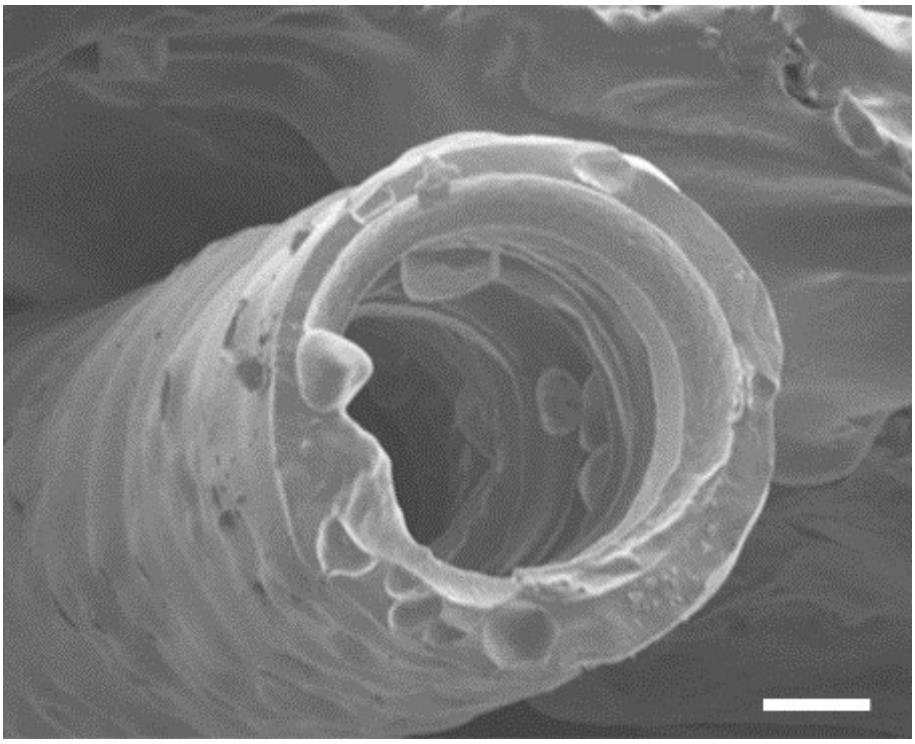

Fig. S6. Cross-sectional SEM image of the ZnS:Cu/PDMS hollow fiber with uniaxial folded microstructures. Scale bar, 50 μm.

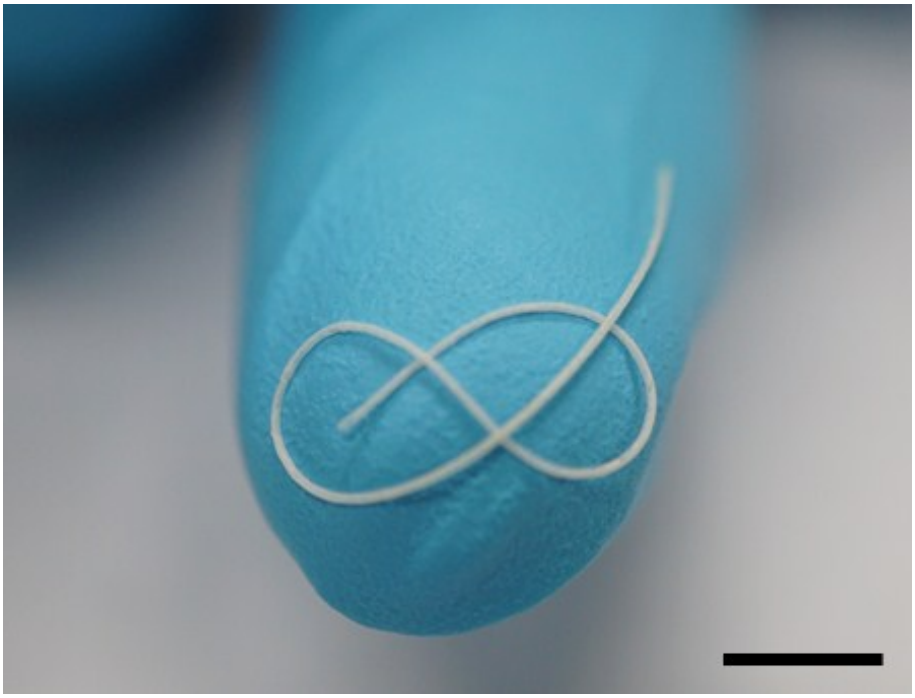

Fig. S7. The photograph of the ZnS:Cu/PDMS hollow fiber on the finger. Scale bar, 0.5 cm.

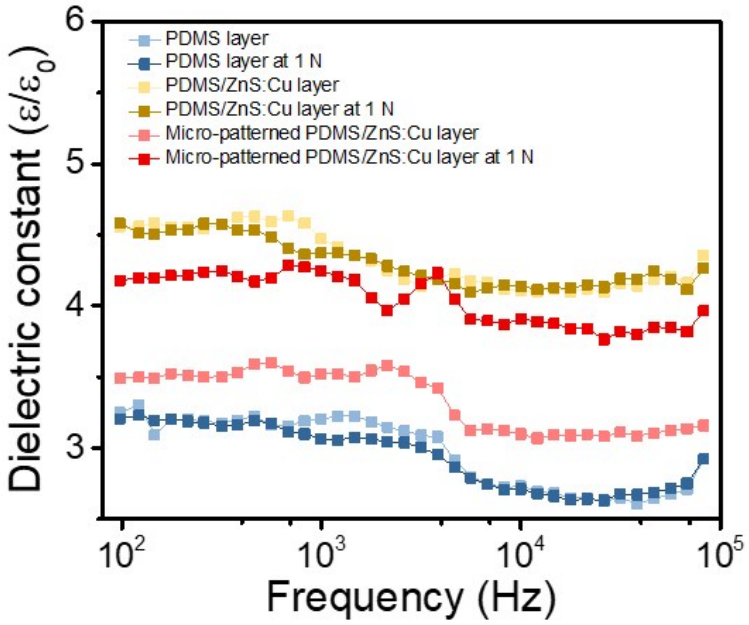

Fig. S8. AC frequency-dependent dielectric constants of PDMS, ZnS:Cu/PDMS composite layers with and without micro-patterns.

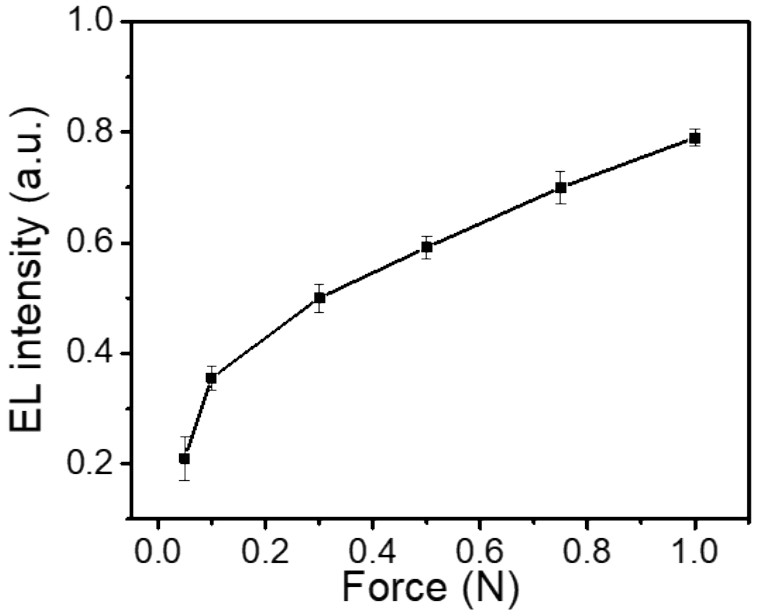

Fig. S9. The dependence of the EL intensity of the FLPS with increasing forces.